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4 **Dry reforming of methane in a temperature-controlled dielectric barrier**
5 **discharge reactor: disclosure of reactant effect**
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26 **Abstract:** Plasma-assisted dry reforming of methane has attracted much research
27 attention because this process simultaneously utilizes greenhouse, methane and carbon
28 dioxide, to produce hydrogen-rich syngas at a relative low temperature. Although it is
29 generally recognized that the gas composition of reactant has great effect on the
30 methane conversion and products distribution, systematic studies that clarify the roles
31 that electron-induced chemistry and thermochemistry play are needed for a full
32 understanding of reactant effect. Here, we compared the reforming performance by
33 varying the ratio of CO₂/CH₄ or O₂/CH₄ at the similar reduced field intensity (E/N) in
34 a temperature-controlled dielectric barrier discharge reactor to elaborate the role of
35 electron-induced chemistry and thermo-chemistry in the dry reforming process. By
36 conducting optical emission spectrum measurement, the enrichment of O atoms was
37 observed at the increased CO₂/CH₄ or O₂/CH₄ ratios. At $T = 293$ K, methane conversion
38 was only dependent on the electron-induced chemistry regardless of the specific
39 reactant gas composition. At a relative high temperature condition, however,
40 thermochemistry could become pronounce when sufficient O atoms were added into
41 the dry reforming process. In contrast, the chemical pathways to the products were
42 overall controlled by the thermochemistry at the tested background temperatures. Due
43 to the conversion of carbon-based products into the carbon dioxide, the conversion of
44 carbon dioxide was influenced by the thermochemistry when the concentration of O
45 atoms was high. Our findings may improve the understanding of reactant effect and the
46 designs of plasma-reformer.
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57 **Key Words:** dry reforming, plasma, carbon dioxide, methane, gas composition
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1. Introduction

Today, under the pressure of serious environmental problems caused by the excessive use of fossil fuels, the demand for renewable and environmental-friendly energy is becoming ever more urgent. The reforming (or gasification) of conventional feedstock as fuel, of which major constituent is carbon and hydrogen, for the production of hydrogen-rich syngas or value-added chemicals has showed promising potential. Various reforming methods, such as partial oxidation, steam reforming, and dry reforming, are designed mainly to produce hydrogen and carbon monoxide and yield typical H₂/CO ratio with each reforming process. Among these reforming processes, the dry reforming of methane, a reaction between methane (CH₄) and carbon dioxide (CO₂), has attracted much research attention because this process simultaneously utilizes and reduces greenhouse [1]. Catalytic processes for the dry reforming are limited by rapid deactivation of the catalysts due to coke formation. Moreover, a requirement of warm-up period to reach activation temperatures also limits the catalytic process in some applications, e.g. in vehicles, which require rapid ignition/start-up from a cold condition. In this reason, studies based on non-thermal plasma (NTP) techniques have been conducted to fill the technical gap [2–5].

Different NTP generation methods [6–10] as well as the combinations of NTP with heterogeneous catalysts [11–16] have been investigated to make the process commercially feasible in terms of energy efficiency and product selectivity. It is generally recognized that the *hotter* plasmas, e.g. arc-jet type plasma and microwave plasma, are superior to the *colder* plasmas, which are typically produced by dielectric barrier discharge (DBD) and corona discharge, in the CH₄ and CO₂ conversion, and H₂ selectivity [17–21]. The advantage of the *colder* plasmas is its low temperature, so it is possibly to obtain useful chemical intermediates that do not reach deep oxidation (CO₂) or cracking (soot) [22–26].

The improvement of the reactant conversion and products distribution using the *colder* plasmas requires a better understanding of plasma chemistry in the reforming process. In previous work, we developed a temperature-controlled DBD reactor. This reactor allows individually controlling the reduced field intensity and reaction

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4 temperature, which govern the electron-induced chemistry and thermochemistry,
5 respectively. As a result, we found that for the dry reforming of CH₄ at CO₂/CH₄=1, the
6 CH₄ conversion was influenced by the electron-induced chemistry while for the partial
7 oxidation of CH₄, the CH₄ conversion was governed by both the electron-induced
8 chemistry and the thermochemistry. However, for both of these reforming processes,
9 the reaction pathways to the products were only affected by the thermochemistry [27,
10 28]. These results indicate that the plasma chemistry involved in the reforming process
11 could be adjusted by the reactant gas composition. In this regard, the reactant gas
12 composition effect needs to be further investigated so that we can get a deeper
13 understanding of the contribution of electron-induced chemistry and thermochemistry
14 to the CH₄ conversion and products distribution.

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25 In the present study, we systematically investigated the effect of reactant gas
26 composition on the dry reforming of CH₄ with the temperature-controlled DBD reactor.
27 The reactant conversion and products selectivities with the different reactant gas
28 compositions were compared at the similar reduced field intensity and background
29 temperature. The performance was evaluated in terms of CH₄ and CO₂ conversions and
30 product selectivity. The role of electron-induced chemistry and thermochemistry in the
31 reforming process was discussed on the basis of the results of performance elevation,
32 optical emission spectroscopy and BOLSIG+ based numerical calculation

33 34 35 36 37 38 39 40 41 **2. Experimental setup**

42 Figure 1 shows the schematic of the setup for the experiment. The experimental
43 setup consisted of a temperature-controlled DBD reactor, a high-voltage supplier, a
44 reactant feeding system, and a measurement system. Similar configuration was used in
45 our previous work [27, 28]. The temperature-controlled DBD reactor includes a coaxial
46 DBD reactor and an electric oven. The coaxial DBD was constructed of a quartz tube
47 with a length of 200 mm and an inner diameter of 20.0 mm, which was used as a
48 dielectric barrier. The outer wall of the quartz tube was wrapped with 45-mm-wide
49 stainless-steel mesh, which was used as a grounding electrode. A stainless-steel rod
50 with a diameter of 17.5 mm was inserted into the quartz tube to serve as a high-voltage
51 electrode. The resulted discharge gap was ~1.3 mm.

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60 An amplifier (20/30 A, Trek) in conjunction with a function generator (AFG 3021B,

Tektronix) was used to generate AC high voltage. The AC high voltage and discharge current were measured by a digital oscilloscope (DPO 4140B, Tektronix) together with a high voltage probe (P 6015A, Tektronix) and a current monitor (6595, Pearson), respectively. The typical value of V_{peak}/V_{rms} was 1.6. V - Q Lissajous method was used to determine the discharge power into the DBD reactor. The charge Q was calculated by measuring a voltage across a 30 nF capacitor, using a voltage probe (TPP 1000, Tektronix). The V - Q Lissajous diagram was averaged over 216 scans, and the discharge power was calculated from the area of the diagram by multiplying the frequency. Optical emission spectroscopy (OES) was conducted by a spectrometer (Acton SP2500i, Princeton Instruments) equipped with a slit (100 μm), a grating (600 grooves mm^{-1}) and a highly sensitive camera (PIXIS-100, Princeton Instruments) with the exposure time of 100 ms.

The flow rate of each component was controlled by a mass flow controller (MFC) (SLA5850, Brooks Instrument). The total flow rate was fixed at 200 ml/min. An electric oven (O series, NDB Co. Ltd.) was used to heat the gas mixture to a target temperature. A homemade ice-water-cooling trap was used to condense liquid products. The feed and product gas were analyzed using an online gas chromatograph (HP 7890A, Agilent) equipped with a flame ionization detector (FID) and two thermal conductivity detectors (TCD).

To characterize the dry reforming process, the CH_4 and CO_2 conversions were defined as:

$$\text{CH}_4 \text{ conversion}(\%) = \frac{\text{moles of CH}_4 \text{ converted}}{\text{moles of CH}_4 \text{ input}} \times 100 \quad (\text{E1})$$

$$\text{CO}_2 \text{ conversion}(\%) = \frac{\text{moles of CO}_2 \text{ converted}}{\text{moles of CO}_2 \text{ input}} \times 100 \quad (\text{E2})$$

The selectivities of the products were calculated as:

$$\text{H}_2 \text{ selectivity}(\%) = \frac{\text{moles of H}_2 \text{ produced}}{2 \times \text{moles of CH}_4 \text{ converted}} \times 100 \quad (\text{E3})$$

$$\text{CO selectivity}(\%) = \frac{\text{moles of CO produced}}{\text{moles of CH}_4 \text{ converted} + \text{moles of CO}_2 \text{ converted}} \times 100 \quad (\text{E4})$$

$$\text{C}_x\text{H}_y \text{ selectivity}(\%) = \frac{X \times \text{moles of C}_x\text{H}_y \text{ produced}}{\text{moles of CH}_4 \text{ converted} + \text{moles of CO}_2 \text{ converted}} \times 100 \quad (\text{E5})$$

and the H₂/CO molar ratio was defined as:

$$\frac{\text{H}_2}{\text{CO}} = \frac{\text{moles of H}_2 \text{ produced}}{\text{moles of CO produced}} \quad (\text{E6})$$

3. Results

3.1. DBD characteristics

Since varying background temperature or reactant gas compositions might affect plasma physics, we investigated the discharge characteristics of the DBD for all experimental conditions. Typical voltage-current waveform and Lissajous diagrams are shown in the Fig. S1 and Fig. S2 of the Supporting Information. In generally, the responses of the lissajous diagrams to the background temperatures for the different reactant gas compositions were similar to that for the dry reforming [28] and partial oxidation process [27]. At $T \leq 673$ K, the lissajous diagram showed a sharp parallelogram shape. The discharge pattern from the DBD with a mixture of CH₄/CO₂/N₂ at $T \leq 673$ K appears to be in the typical filamentary micro-discharge mode [29] of DBD. At $T=773$ K, however, the diagram changes from a sharp parallelogram shape into a smooth shape. This change is due to the significant reduction in the resistances of the gas gap and the barrier [28]. Because of these significant resistances' reduction, the discharge mode at 773 K can be characterized as the co-existence of micro-discharges and resistive waste of electrical power [28]. Thus, in this study, the maximum background temperature was set at 673 K.

In the present study, the reduced field intensity (E/N) was varied by the background temperature. The E/N value was estimated by $E/N \approx U_b/(dN)$, where E is the averaged electric field, N is the gas number density, d is the gas gap distance, and U_b is the breakdown voltage in the gas gap. U_b could be calculated from $U_b = U_{on}/(1 + C_g/C_d)$, where U_{on} is the onset voltage, C_d is the effective capacitances of the dielectric barrier, and C_g is the effective capacitances of the gas gap which can be calculated via $C_g =$

$C_d C_{tot} / (C_d - C_{tot})$, where C_{tot} is the effective capacitance of the total system. Among these values, U_{on} , C_d , and C_{tot} could be determined from the lissajous diagrams based on the well-developed DBD model [30]. Table 1 summarizes the estimated E/N values for all tested conditions. As shown in the Table 1, the E/N value was more sensitive to the background temperature than to the reactant gas compositions.

In addition, we investigated the optical emission spectra of the DBD for the different reactant gas compositions. Each spectrum was normalized with the measured light intensity of the N_2 (C-B) emission band that peaked at 380.3 nm. As shown in Fig. 2a, the emission spectrum of the DBD dry reforming was dominated by the emission of N_2^* related bands, such as N_2 C-B and N_2^+ B-X. The CH bands peaked at 431.4 nm and C_2 swan peaked at 516.5 nm were also observed indicating the electron dissociation of the CH_4 . As compared to the condition of $CO_2/CH_4=1$, an atomic line peaked at 777.1 nm was appeared in the condition of $CO_2/CH_4=4$ indicating the enrichment of the O atoms (Fig. 2b). When O_2 was added into the dry reforming process (Fig. 2c), the bands of CH were reduced by half (as compared to the condition of $CO_2/CH_4=1$) and the bands of C_2 swan disappeared, while the O atom line also appeared.

3.2. Reforming at room temperature

3.2.1. The effect of CO_2/CH_4 ratio on the dry reforming

Figure 3 shows the effect of CO_2/CH_4 ratio on the dry reforming of CH_4 at $T=293$ K and fixed discharge power ($P_{dis}=10$ W). When CO_2/CH_4 ratio was increased from 0.5 to 4, the conversions of CH_4 and CO_2 were kept at around 7.5 % and 3.3% (Fig.3a), respectively. Although the ratio of CO_2/CH_4 did not significantly affect the CH_4 and CO_2 conversion, it obviously altered the product distribution; the selectivities of H_2 , C_2H_6 , C_2H_4 , C_3H_8 , and other HCs (Fig.3b) were decreased from 46.8 to 40.2 %, 21.4 to 3.1%, 0.9 to 0.1, 1.8 to 0.2 and 0.8 to 0.1, respectively, while the selectivity of CO increased from 58.7 to 75.9%. It is worth mentioning that the production of CO was mainly attributed to the decomposition of CO_2 , because the amount of produced CO was linearly dependent on the conversion of CO_2 as shown in the Supporting Information of Fig. S3. However, carbons would be more or less produced from the dry

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4 reforming process and deposited on the DBD reactor. When the concentration of O
5 atom is high, these carbons are possible oxidized into the CO which might be
6 responsible for the abrupt change in the CO selectivity at a relative high CO_2/CH_4
7 ($\text{CO}_2/\text{CH}_4=1.5$) condition. In addition, due to the varied H_2 and CO selectivity the ratio
8 of H_2/CO decreased from 2.1 to 0.4.
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13 **3.2.2. The effect of O_2 addition on the dry reforming**

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15 Figure 4 shows the effect of O_2 percentage on the dry reforming of CH_4 at
16 $\text{CH}_4/\text{CO}_2=1$, $T=293$ K, and $P_{dis}=10$ W. The addition of O_2 did not affect the CH_4
17 conversion but obviously influenced the CO_2 conversion and O_2 conversion; when
18 increasing O_2/CH_4 from 0.2 to 0.8, the conversion of CH_4 was kept at around 8.2%, but
19 the conversion of CO_2 and O_2 decreased from 2.8 to 1.3% and 55.7 to 12.7%
20 respectively (Fig. 4a). Regarding the products (Fig. 4b), the selectivity towards H_2 ,
21 C_2H_6 , C_2H_4 , C_3H_8 and other HCs decreased from 44.4 to 16.2%, 13.3 to 1.7%, 0.3 to
22 0.06%, 0.8 to 0.04%, 0.4 to 0.02%, respectively, while the selectivity towards CO
23 increased from 59.4 to 84.6%, and the ratio of H_2/CO decreased from 1.0 to 0.3. It
24 seems that the response of products distribution to the varying O_2/CH_4 were much
25 significant than that to the varying CO_2/CH_4 . In addition, when O_2 was added into the
26 dry reforming process, the production of CO was not due only to the conversion of CO_2 ,
27 because the selectivity of CO was even increased with the decrease of CO_2 conversion.
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40 **3.3. Dry reforming at a relative high temperature**

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42 Figure 5 shows the CH_4 and CO_2 conversion, and products selectivities with
43 different CO_2/CH_4 ratios at $T=493$ K and $P_{dis}=10$ W. Unlike the CH_4 conversion at room
44 temperature ($T=293$ K), the CH_4 conversion at $T=473$ K was increased (7.7 to 10.3%)
45 with the increase of CO_2/CH_4 ratio (0.5 to 4). In contrast, the response of CO_2 , H_2 , HCs
46 and CO to the CO_2/CH_4 ratio at $T=493$ K was similar to these at $T=293$ K; when
47 increasing CO_2/CH_4 ratio from 0.5 to 4, the conversion of CO_2 did not significantly
48 change, while the selectivities of H_2 and HCs decreased, and the selectivity of CO
49 increased as shown in Fig. 5. These results indicate that the reaction pathways of CO_2
50 conversion and products formation was not significantly changed with the CO_2/CH_4
51 ratio at higher background temperature condition.
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The increase in O_2/CH_4 ratio ($CO_2/CH_4=1$) led to the obvious increase of CH_4 conversion at $T=473$ K (Fig. 6). In addition, as compared to the condition at $T=293$ K, the CO_2 conversion, and H_2 , CO and HCs selectivity seem more sensitive to the O_2/CH_4 ratio at $T=473$ K, because these values changed more significantly with the O_2/CH_4 ratio at $T=473$ K than those with the O_2/CH_4 ratio at $T=293$ K.

3.4. Effect of reduced field intensity on dry reforming

Figure 7 shows the effect of reduced field intensity (E/N) on CH_4 conversion, CO_2 conversion and products selectivities with different reactant gas compositions at fixed discharge power ($P_{dis}=10$ W). When adding O_2 into the dry reforming process, the CO_2/CH_4 value was kept to be 1. The E/N value was modified by varying the background temperature. It should be noted that the maximum E/N value was limited to ~ 165 Td, because the background temperature was controlled less than 673 K by considering the DBD mode [28]. The results of the dry reforming at 673 K were abstracted from our previous work [22, 28].

As shown in Fig. 7a, when the E/N was increased from 70 to 160 Td, the CH_4 conversion increased from 7.8 to 11.5% for $CO_2/CH_4=1$. At the E/N value between 70 to 80 Td (corresponding to $T=293$ K), no obvious difference was observed between different reactant gas compositions. At the higher E/N value, however, the CH_4 decreased in the order of $O_2/CH_4=0.8 \gg CO_2/CH_4=4 > CO_2/CH_4=1$ at the comparable E/N value. Regarding to the CO_2 conversion (Fig. 7b), at the comparable E/N value, the CO_2 conversion decreased in the order of $CO_2/CH_4=1 \approx CO_2/CH_4=4 > O_2/CH_4=0.8$ at $E/N \leq 120$ Td, while it decreased in the order of $CO_2/CH_4=1 > CO_2/CH_4=4 > O_2/CH_4=0.8$ at $E/N > 120$ Td.

As for the products, the selectivity of H_2 decreased with the increase of E/N value (Fig. 8a), and it decreased in the order of $CO_2/CH_4=1 > CO_2/CH_4=4 > O_2/CH_4=0.8$ regardless of the specific E/N value. However, the selectivity of CO increased with the E/N value for the $O_2/CH_4=0.8$ (Fig. 8b), while it decreased with the E/N value for the $CO_2/CH_4=1$ and $CO_2/CH_4=4$. It decreased in the order of $O_2/CH_4=0.8 > CO_2/CH_4=4 > CO_2/CH_4=1$. Thus, the H_2/CO value could be varied in a wide range (Fig. 8d). In contrast to the trend of the selectivity of CO , the selectivity of HCs decreased with the

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4 E/N value for the $O_2/CH_4=0.8$ (Fig. 8d), while it increased with the E/N value for the
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6 $CO_2/CH_4=1$ and $CO_2/CH_4=4$.

7 8 **4. Discussion**

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10 We have shown that the variation of the reactant gas composition affected CH_4 and
11 CO_2 conversion, and products distribution. This should be possibly attributed to the
12 modified electron-induced chemistry or the thermochemistry by the change of the
13 reactant. Table 2 summarized important reactions that are responsible for the plasma-
14 assisted dry reforming with the tested reactant gas compositions [31–33]. At a low
15 temperature condition, the plasma-assisted dry reforming process is initiated by the
16 electron-impact dissociation reactions rather than thermal decomposition. The
17 efficiencies of these dissociation reactions depend on electron density and electron
18 energy, which are respectively determined by the energy density and the reduced field
19 intensity (E/N) [27, 28].
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29 A calculation from BOLSIG+ software [34] (Fig. S4 of the Supporting Information)
30 indicated that, in the tested E/N value range, the reaction (R1) is responsible for ~83%
31 of the total electron dissociation of CH_4 , while reactions (R2) and (R3) are responsible
32 for ~13% and ~3%, respectively. It is worth mentioning that the contribution of the
33 reactions between metastable N_2^* and CH_4 could not be ignore due to the high
34 concentration of the metastable N_2^* in the reforming process (Fig. 2). However, these
35 reactions could be considered as indirect electron dissociation of CH_4 by considering
36 the net reactions of following reactions: $e + N_2 \rightarrow N_2^* + e$, $N_2^* + CH_4 \rightarrow$ products (CH_x
37 + H_y , $x + y = 4$) + N_2 . CO_2 conversion is mainly due to the reaction (R4). Note that no
38 NO_x was observed in the OES measurement.
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48 During electron-impact dissociation reactions, many other reactive species, such as
49 O and H atoms and OH radicals are produced. These reactive species may either
50 facilitate further CH_4 conversion through reactions (R5–R7), or they might be
51 consumed to produce products. As a richest carbon-containing intermediate product
52 from the CH_4 conversion, CH_3 radicals are also important to the CH_4 conversion
53 because it might be responsible for the CH_4 backward reaction (as R8 in R9). Regarding
54 the products, H_2 is mainly produced from the H radical recombination and the reactions
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of H with CH₄, HO₂ and HCO, whereas CO is mainly produced from electron-impact dissociation of CO₂ as well as the HCO oxidation and the reaction of HCO with CH₃ and H atoms, and hydrocarbons are produced from the recombination of CH_x ($x = 1 - 3$) radicals.

In our previous work [28], by independently controlling the background temperature and the reactor pressure to adjust similar reduced field intensity, we have proposed that for the CO₂/CH₄=1, the electron-induced chemistry controlled the decomposition of CH₄ and CO₂, while the rest of chemical reactions to the products were governed by thermochemistry. In this regard, the result of CO₂/CH₄=1 could be considered as a reference result to get a better understanding of the plasma chemistry with different reactant gas compositions.

In this study, at the room temperature condition, the CH₄ conversion was not influenced by the reactant compositions indicating that the CH₄ conversion was controlled by the electron-induced chemistry. It is worth mentioning that the enrichment of O atoms was observed with CO₂/CH₄=4 and O₂/CH₄=0.8 by the OES measurement as shown in Fig. 2. These enrichments could be attributed to the increased electron-impact dissociation of CO₂ for CO₂/CH₄=4 as evidenced by the higher selectivity of CO (Fig. 3b), and the effective electron-impact dissociation of O₂ for O₂/CH₄=0.8 as evidenced by the low threshold level for the electron-impact dissociation of O₂ (5.1 eV [35]) as compared to that of CO₂ (8.1 eV [36]). It seems that these enriched O atoms were not used for the CH₄ conversion at the room temperature. In contrast, at a relatively high temperature condition, the CH₄ conversion with CO₂/CH₄=4 and especially with O₂/CH₄=0.8 was enhanced as compared to that with CO₂/CH₄=1 at the similar E/N value. Considering the improved CH₄ conversion with CO₂/CH₄=1 at higher temperature condition was solely due to the enhanced E/N value [28], thermochemistry more or less affected the CH₄ conversion with CO₂/CH₄=4 and O₂/CH₄=0.8.

Figure 9a shows the reaction constants for the reactions related to CH₄ conversion under different background temperatures, where the reaction constants were obtained from [37]. The reaction constants of R5–R7 significantly increases from 5×10^{-18} to 7

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4 $\times 10^{-14} \text{ cm}^3 \text{ molecule}^{-1} \text{ s}^{-1}$, 7×10^{-18} to $4 \times 10^{-13} \text{ cm}^3 \text{ molecule}^{-1} \text{ s}^{-1}$, and 8×10^{-19} to $2 \times$
5 $10^{-14} \text{ cm}^3 \text{ molecule}^{-1} \text{ s}^{-1}$, respectively, in a temperature range of 293 – 673 K. Meanwhile,
6 the CH₄ backward related reactions, R8 and R9, are not affected by the background
7 temperature. These results indicate that at $T=293$ K, the low reaction constants of CH₄
8 conversion-related reactions contributed to the insensitive of the CH₄ conversion to the
9 varying reactant gas composition and the CH₄ conversion is dependent of the electron-
10 induced chemistry. At the higher temperatures, however, due to the increased reaction
11 constants of the R5–R7, thermochemistry might control the CH₄ conversion when
12 sufficient O containing active species (e.g. the condition of CO₂/CH₄=4, O₂/CH₄=0.8)
13 was presented in the dry reforming process. According to our calculation using
14 CHEMKIN-PRO package with modified USC Mech II mechanism [27, 32, 33], R6 is
15 responsible for the enhancement of CH₄ conversion by thermochemistry at the high
16 temperature conditions.

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29 However, the reaction constants of H₂, CO and HCs related reactions are typically
30 high and less sensitive to the background temperatures (Fig. 9b–9c). This led to the
31 involvement of O containing active species in the H₂ and CO production and
32 consumption process at all background temperatures, and thus the thermochemistry
33 affected the products selectivity regardless of the specific background temperature. It
34 should be noted that when O₂ was not added into the dry reforming process, CO was
35 mostly produced from the electron-impact dissociation of CO₂ because the amount of
36 produced CO was linearly dependent on the conversion of CO₂ as shown in Fig. S3 of
37 the Supporting Information. Meanwhile, CO selectivity was also obviously affected by
38 the thermochemistry because it was decreased with the background temperature. This
39 decreased CO selectivity was accompanied by the increased HCs selectivity indicating
40 less O containing active species was used for the CO production. We propose that the
41 O containing active species was used in the H₂ consumption at the higher temperature
42 condition because the reaction constants of R16 and R17 were increased with the
43 background temperature as shown in Fig. 9c. This hypothesis is supported by the fact
44 that the H₂ selectivity was decreased with the background temperature.

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60 However, with the addition of O₂, CO was mainly produced from the oxidation of

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4 HCs. This argument is supported by the evidence that the addition of O_2 had opposite
5 effect on the CO selectivity and CO_2 conversion. According to our previous work
6 dealing with the partial oxidation of CH_4 , R18 is the major pathway for the CO
7 production when O_2 was presented [27]. The significant consumption of carbon-based
8 active species was also confirmed by the OES as shown in Fig. 2. Since the CH_3 was
9 mainly used for the CO production, the low selectivity of HCs could be understood.
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11 Moreover, the addition of O_2 enriched O containing active species which lowered the
12 selectivity of the H_2 .
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19 It is worth mentioning that with the similar reactant, the maximum conversion
20 efficiency of CH_4 in this study was 4.9 mg/kJ, which is much less than that of CH_4 (~20
21 mg/kJ) with the arc-jet type plasma [38], where the arc-jet type plasma has a localized
22 high-temperature (over several thousand kelvins [38]) environment. Our finding
23 emphasizes that both the sufficient active species and a relatively high temperature are
24 necessary to improve the CH_4 conversion. However, these ways to increase the CH_4
25 conversion also resulted in a vigorous oxidation environment which prevents the high
26 selectivity of H_2 and HCs. Because the pathways to the products are controlled by the
27 thermochemistry, it is possible to adjust the products distribution by controlling the
28 reaction time of the dry reforming products. Such research is underway and will be
29 reported in the near future.
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41 5. Conclusions

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43 We have investigated the dry reforming of methane to produce hydrogen and
44 carbon monoxide in a temperature-controlled dielectric barrier discharge reactor. In
45 particular, the performance of different CO_2/CH_4 ratios and O_2/CH_4 ratios were
46 compared at the similar reduced field intensity to deeper understanding of the role of
47 electron-induced chemistry and thermochemistry in the dry reforming process, where
48 the reduced field intensity was adjusted by the background temperature. We found that
49 at the room temperature condition, due to the low reaction constants of the reactions
50 between CH_4 and O containing active species, the CH_4 conversion was attributed to the
51 electron-induced chemistry rather than the thermochemistry. Two factors, relatively
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high temperature and sufficient O containing active species, are necessary to make the thermochemistry important in the CH₄ conversion. In contrast, the products distribution (H₂, CO, HCs) was always controlled by the thermochemistry regardless of the specific background temperature. When the concentration of O containing active species was high, the excessive oxidation of the HCs and CO resulted in decrease of CO₂ conversion. Thus, CO₂ conversion is possibly affected by the thermochemistry even at the room temperature.

Based on the current observation, a vigorous oxidation environment is beneficial to the CH₄ conversion in the DBD reactor. The improvement of the conversion of CO₂ and the selectivity of target products (such as H₂) in such a vigorous oxidation environment is our ongoing work. Modeling works are required to fully understand the reaction pathway and to predict a way to tailor a target product.

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References

- [1] Aramouni N A K, Touma J G, Tarboush B A, Zeaiter J and Ahmad M N 2018 *Renew. Sust. Energ. Rev.* **82** 2570-85
- [2] Wang X, Gao Y, Zhang S, Sun H, Li J and Shao T 2019 *Appl. Energy* **243** 132-44
- [3] Ray D, Reddy P M K and Subrahmanyam C 2018 *Catal. Today* **309** 212-8
- [4] Khoja A H, Tahir M and Amin N A S 2019 *Energ. Convers. Manage.* **183** 529-60
- [5] Brune L, Ozkan A, Genty E, de Bocarmé T V and Reniers F 2018 *J. Phys. D: Appl. Phys.* **51** 234002
- [6] Ray D, Nepak D, Janampelli S, Goshal P and Subrahmanyam C 2019 *Energy Technol.* **7** 1801008
- [7] Wu S, Liu X, Mao W, Chen W, Liu C and Zhang C 2018 *J. Appl. Phys.* **124** 243302
- [8] Wang Y, Yang H and Tu X 2019 *Energ. Convers. Manage.* **187** 593-604
- [9] Wu Z, Zhou W, Hao X and Zhang X 2019 *Energy* (DOI: 10.1016/j.energy.2019.116265)

- 1
2
3
4 [10] Wu Z, Hao X, Zhou W, Yao S, Han J, Tang X and Zhang X 2018 *Plasma Sources Sci. Technol.*
5 **27** 115002
6
7
8 [11] Zhang X and Cha M S 2016 *J. Phys. D: Appl. Phys.* **49** 175201
9
10 [12] Yao S, Weng S, Tang Y, Zhao C, Wu Z, Zhang X, Yamamoto S and Kodama S 2016 *Vacuum*
11 **126** 16-23
12
13 [13] Wu Z, Zhu Z, Hao X, Zhou W, Han J, Tang X, Yao S and Zhang X 2018 *J. Hazard. Mater.* **347**
14 48-57
15
16 [14] Lian H, Liu J, Li X, Zhu X, Weber A Z and Zhu A 2019 *Chem. Eng. J.* **369** 245-52
17
18 [15] Xin Y, Sun B, Zhu X, Yan Z, Zhao X and Sun X 2018 *Int. J. Hydrogen Energy* **43** 9503-13
19
20 [16] Zhang X and Cha M S 2015 *J. Phys. D: Appl. Phys.* **48** 215201
21
22 [17] Zhang H, Wang W, Li X, Han L, Yan M, Zhong Y and Tu X 2018 *Chem. Eng. J.* **345** 67-78
23
24 [18] Rollier J, Gonzalez-Aguilar J, Petitpas G, Darmon A, Fulcheri L and Metkemeijer R 2007
25 *Energy Fuels* **22** 556-60
26
27 [19] Li Z, Yang T, Yuan S, Yin Y, Devid E J, Huang Q, Auerbach D and Kleyn A W 2019 *J. Energy*
28 *Chem.* (DOI: 10.1016/j.jechem.2019.10.007)
29
30 [20] Tao Y, Jun S, Tangchun R, Jiao L I, Pan C and Yongxiang Y 2018 *Plasma Sources Sci. Technol.*
31 **20** 65502
32
33 [21] Bidgoli A M, Ghorbanzadeh A, Lotfalipour R, Roustaei E and Zakavi M 2017 *Energy* **125** 705-
34 15
35
36 [22] Wang W, Snoeckx R, Zhang X, Cha M S and Bogaerts A 2018 *J. Phys. Chem. C* **122** 8704-23
37
38 [23] Snoeckx R, Wang W, Zhang X, Cha M S and Bogaerts A 2018 *Sci. Rep.-UK* **8** 15929
39
40 [24] Sheng Z, Kameshima S, Yao S and Nozaki T 2018 *J. Phys. D: Appl. Phys.* **51** 445205
41
42 [25] Bogaerts A and Neyts E C 2018 *ACS Energy Lett.* **3** 1013-27
43
44 [26] Wang L, Yi Y, Wu C, Guo H and Tu X 2017 *Angew. Chem., Int. Ed.* **56** 13679-83
45
46 [27] Zhang X and Cha M S 2015 *P. Combust. Inst.* **35** 3447-54
47
48 [28] Zhang X and Cha M S 2013 *J. Phys. D: Appl. Phys.* **46** 415205
49
50 [29] Kogelschatz U 2003 *Plasma Chem. Plasma Process.* **23** 1-46
51
52 [30] Wagner H, Brandenburg R, Kozlov K V, Sonnenfeld A, Michel P and Behnke J F 2003
53 *Vacuum* **71** 417-36
54
55 [31] Zhou L M, Xue B, Kogelschatz U and Eliasson B 1998 *Energy Fuels* **12** 1191-9
56
57
58
59
60

1
2
3
4 [32] Wang H, You X, Joshi A V, Davis S G, Laskin A, Egolfopoulos F and Law C K 2007

5 http://ignis.usc.edu/USC_Mech_II.htm

6
7 [33] Seinfeld J H and Pandis S N 1998 *Atmospheric chemistry and physics: from air pollution to*

8 *climate change* (New York: John Wiley & Sons) p 246-249

9
10 [34] Hagelaar G and Pitchford L C 2005 *Plasma Sources Sci. Technol.* **14** 722

11 [35] Chen J and Davidson J H 2003 *Plasma Chem. Plasma Process.* **23** 501-18

12 [36] Lee D H, Kim K, Cha M S and Song Y 2007 *P. Combust. Inst.* **31** 3343-51

13 [37] <https://kinetics.nist.gov/> last accessed at November 5, 2019

14 [38] Hwang N, Song Y H, Cha M S, 2010 *IEEE Trans. Plasma Sci.* **38** 3291–3299.

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Figure Caption

Figure 1. Schematic diagram of the experimental setup.

Figure 2. Typical discharge emission spectra normalized by the N_2^* emission band at $P_{dis} = 10$ W: (a) $CO_2/CH_4=1$, (b) $CO_2/CH_4=4$, and (c) $O_2/CO_2/CH_4=0.8:1:1$.

Figure 3. Effect of CO_2/CH_4 value on the (a) CH_4 , CO_2 conversion and H_2/CO , and (b) H_2 , CO , C_2H_4 , C_2H_6 , C_3H_6 , and other HCs selectivity at $P_{dis} = 10$ W, $T=293$ K.

Figure 4. Effect of O_2/CH_4 value on the dry reforming of CH_4 (a) CH_4 , CO_2 , O_2 conversion and H_2/CO , and (b) H_2 , CO , C_2H_4 , C_2H_6 , C_3H_6 , and other HCs selectivity at $P_{dis} = 10$ W, $T=293$ K.

Figure 5. Effect of CO_2/CH_4 value on the (a) CH_4 , CO_2 conversion and H_2/CO , and (b) H_2 , CO , C_2H_4 , C_2H_6 , C_3H_6 , and other HCs selectivity at $P_{dis} = 10$ W, $T=473$ K.

Figure 6. Effect of O_2/CH_4 value on the dry reforming of CH_4 (a) CH_4 , CO_2 , O_2 conversion and H_2/CO , and (b) H_2 , CO , C_2H_4 , C_2H_6 , C_3H_6 , and other HCs selectivity at $P_{dis} = 10$ W, $T=473$ K.

Figure 7. Effect of E/N value on the dry reforming of CH_4 (a) CH_4 conversion and (b) CO_2 conversion at $P_{dis} = 10$ W.

Figure 8. Effect of E/N value on the dry reforming of CH_4 (a) H_2 selectivity, (b) CO selectivity, (c) H_2/CO , and (d) HCs selectivity at $P_{dis} = 10$ W.

Figure 9. Reaction constants under different reaction temperatures: (a) CH_4 conversion; (b) Competing reaction and CH_4 backward reaction; (c) H_2 production and consumption; (d) CO production and consumption.

Table 1. Summary of E/N values for tested conditions.

Gas composition	Absolute pressure (bar)	T (K)	E/N (Td)
CO ₂ /CH ₄ =1	1	293	70.4
		473	112.1
		573	135.8
		673	159.5
CO ₂ /CH ₄ =4	1	293	75.3
		473	118.2
		573	140.5
		673	165.2
O ₂ /CH ₄ =0.8 when CO ₂ /CH ₄ =1	1	293	80.3
		473	125.4
		573	150.8
		673	175.1

Table 2. Important reactions related to reactant conversion and products formation

Reaction type	Reaction	Number
CH ₄ and CO ₂ conversion	CH ₄ +e → CH ₃ +H+e	R1
	CH ₄ +e → CH ₂ +H ₂ +e	R2
	CH ₄ +e → CH+H+H ₂ +e	R3
	CO ₂ +e → CO + O	R4
	CH ₄ +O → CH ₃ +OH	R5
	CH ₄ +OH → CH ₃ +H ₂ O	R6
	CH ₄ +H → CH ₃ +H ₂	R7
CH ₄ backward reaction	CH ₃ +H → CH ₄	R8
	CH ₃ +HCO → CH ₄ +CO	R9
Competing reaction	CH ₃ +OH → CH ₃ OH	R10
	CH ₃ +O → CH ₂ O+H	R11
	CH ₃ +O ₂ → CH ₃ O ₂	R12
H ₂ production	H+H+M → H ₂ +M	R13
	CH ₄ +H → CH ₃ +H ₂	R7
	H+HO ₂ → O ₂ +H ₂	R14
	HCO+H → CO+H ₂	R15
H ₂ consumption	H ₂ +O → OH+H	R16
	H ₂ +OH → H ₂ O+H	R17
CO production	HCO+O ₂ → CO+HO ₂	R18
	HCO+OH → CO+H ₂ O	R19
	HCO+O → CO+OH	R20
	CH ₃ +HCO → CH ₄ +CO	R9
	HCO+H → CO+H ₂	R15
CO consumption	CO+O → CO ₂	R21
	CO+OH → CO ₂ +H	R22
	HO ₂ +CO → OH+CO ₂	R23

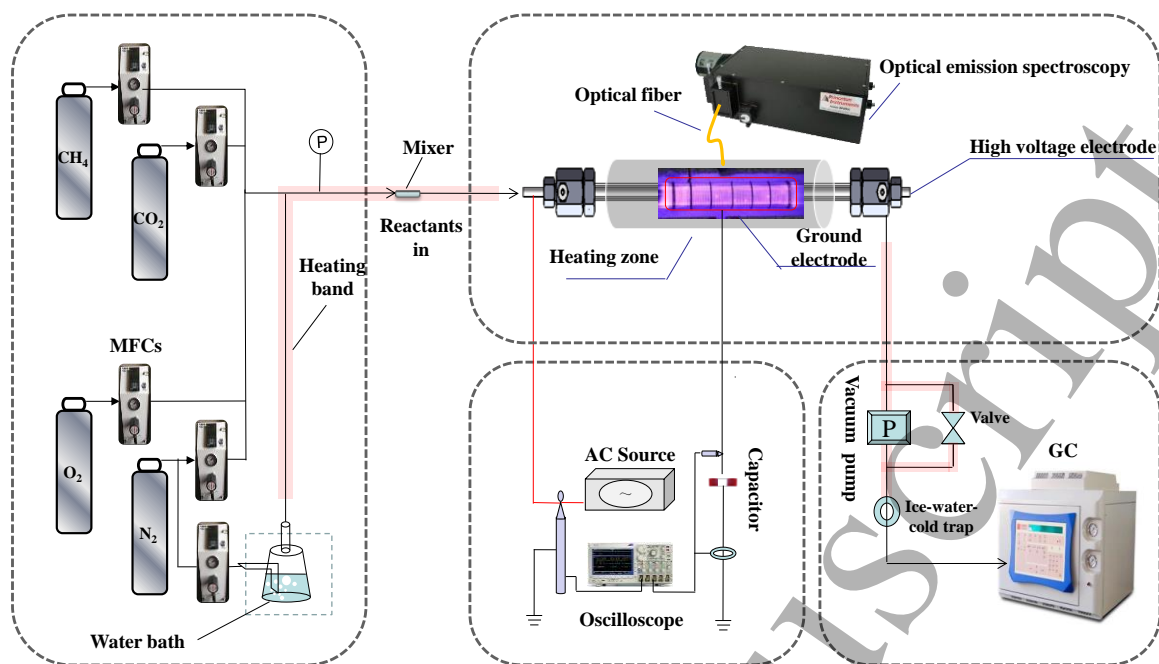


Figure 1. Schematic diagram of the experimental setup.

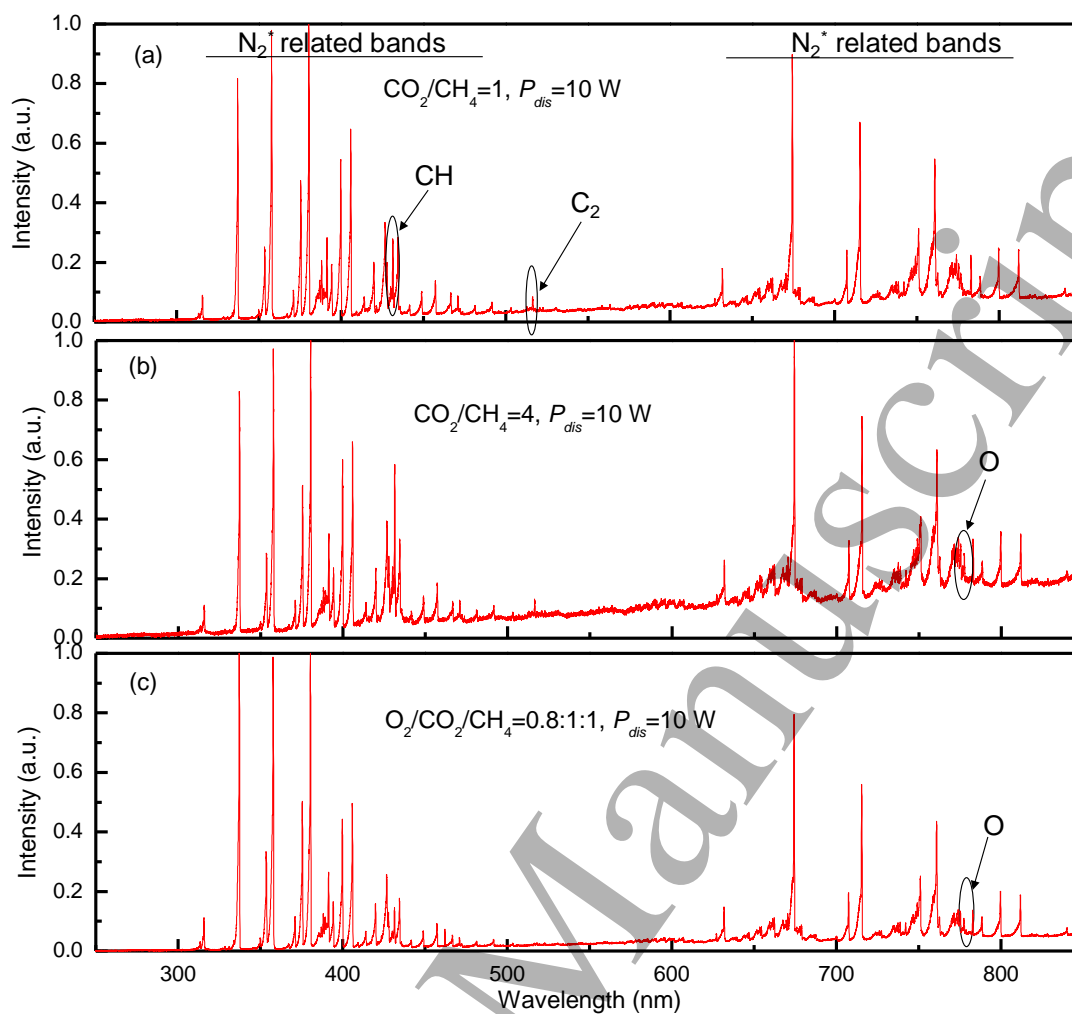


Figure 2. Typical discharge emission spectra normalized by the N_2^* emission band at $P_{dis} = 10$ W: (a) $CO_2/CH_4=1$, (b) $CO_2/CH_4=4$, and (c) $O_2/CO_2/CH_4=0.8:1:1$.

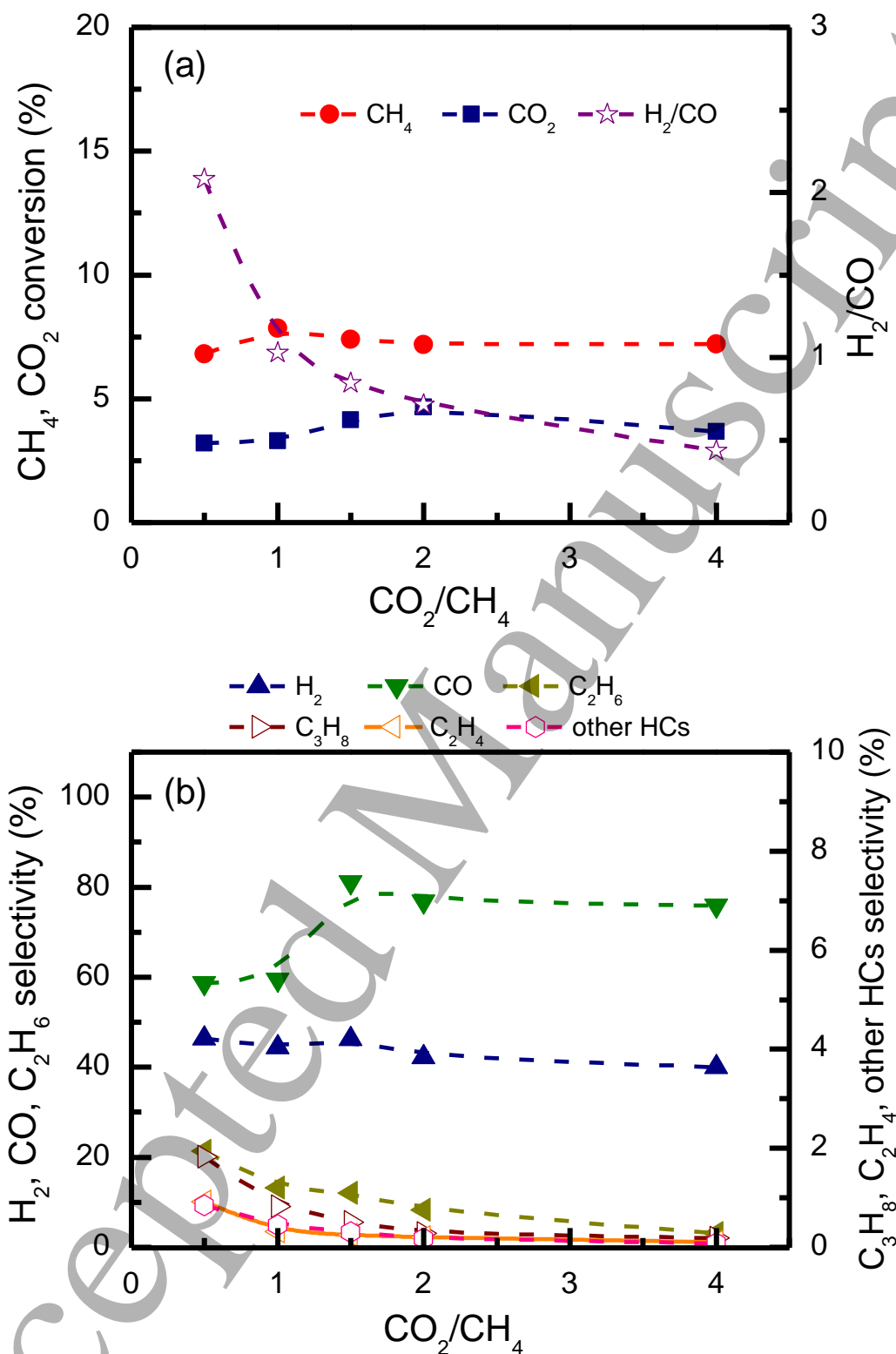


Figure 3. Effect of CO_2/CH_4 value on the (a) CH_4 , CO_2 conversion and H_2/CO , and (b) H_2 , CO , C_2H_4 , C_2H_6 , C_3H_8 , and other HCs selectivity at $P_{dis} = 10$ W, $T=293$ K.

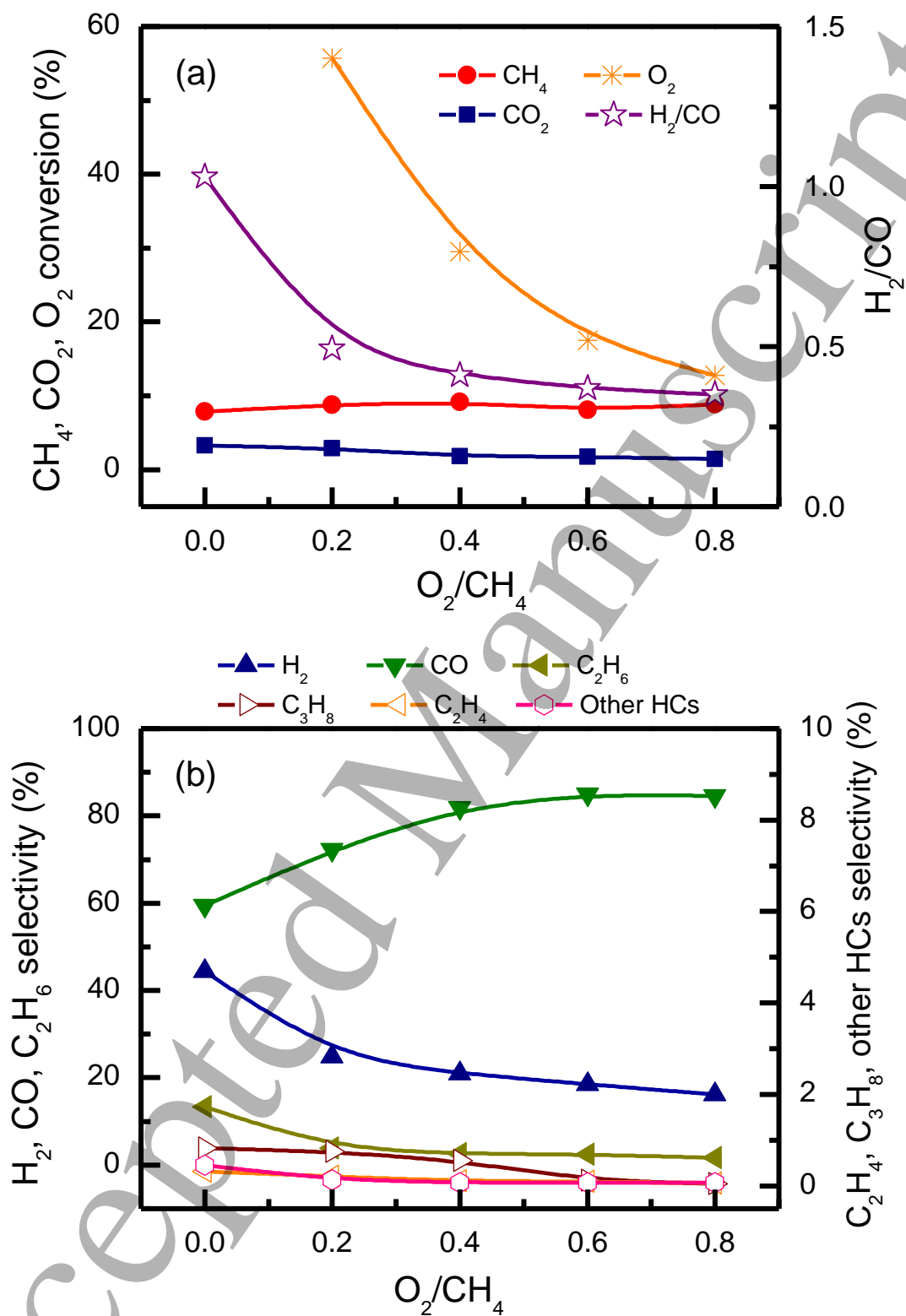


Figure 4. Effect of O_2/CH_4 value on the dry reforming of CH_4 (a) CH_4 , CO_2 , O_2 conversion and H_2/CO , and (b) H_2 , CO , C_2H_4 , C_2H_6 , C_3H_8 , and other HCs selectivity at

$P_{dis} = 10$ W, $T = 293$ K.

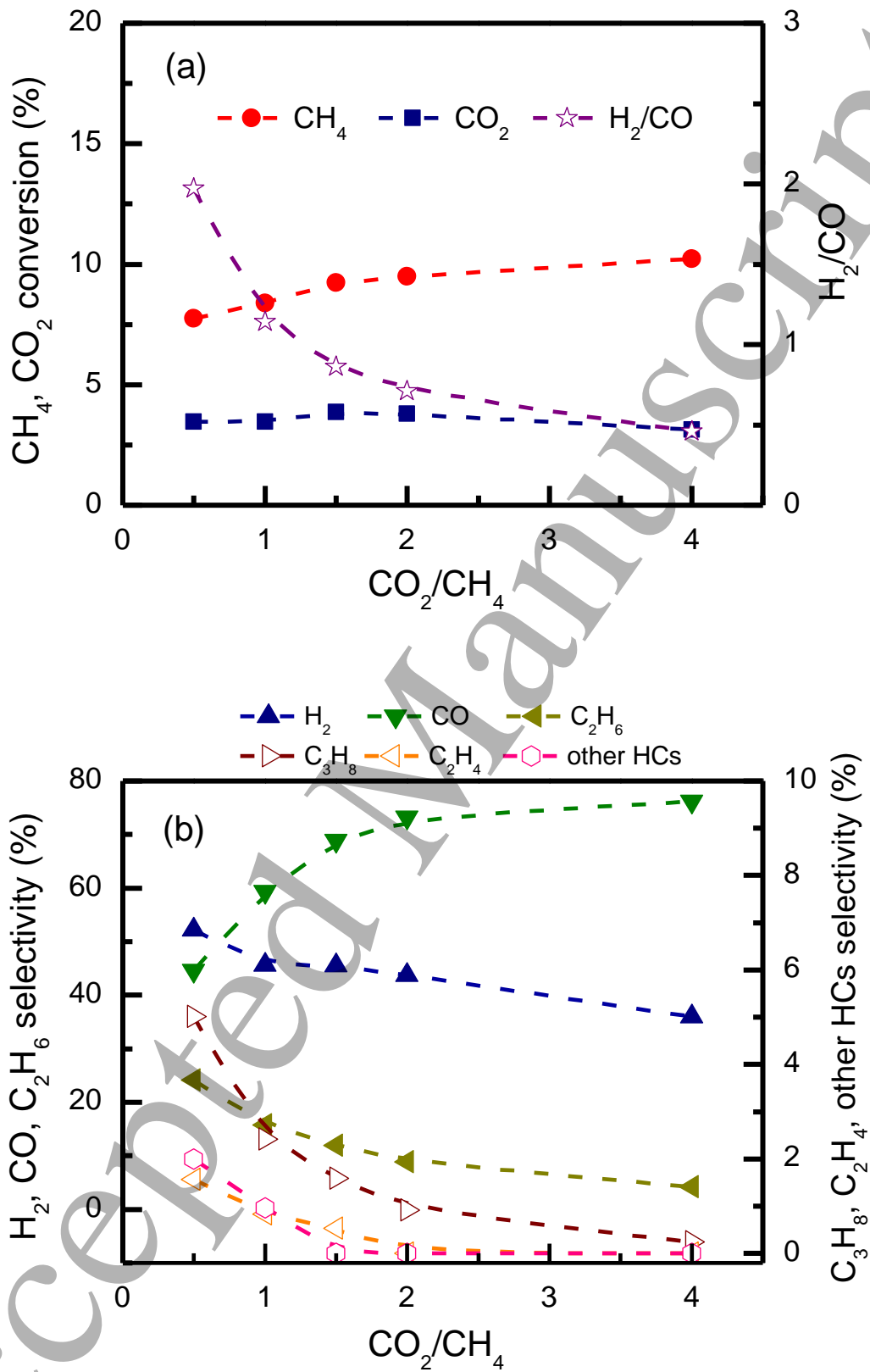


Figure 5. Effect of CO_2/CH_4 value on the (a) CH_4 , CO_2 conversion and H_2/CO , and (b)

H_2 , CO , C_2H_4 , C_2H_6 , C_3H_8 , and other HCs selectivity at $P_{dis} = 10$ W, $T = 473$ K.

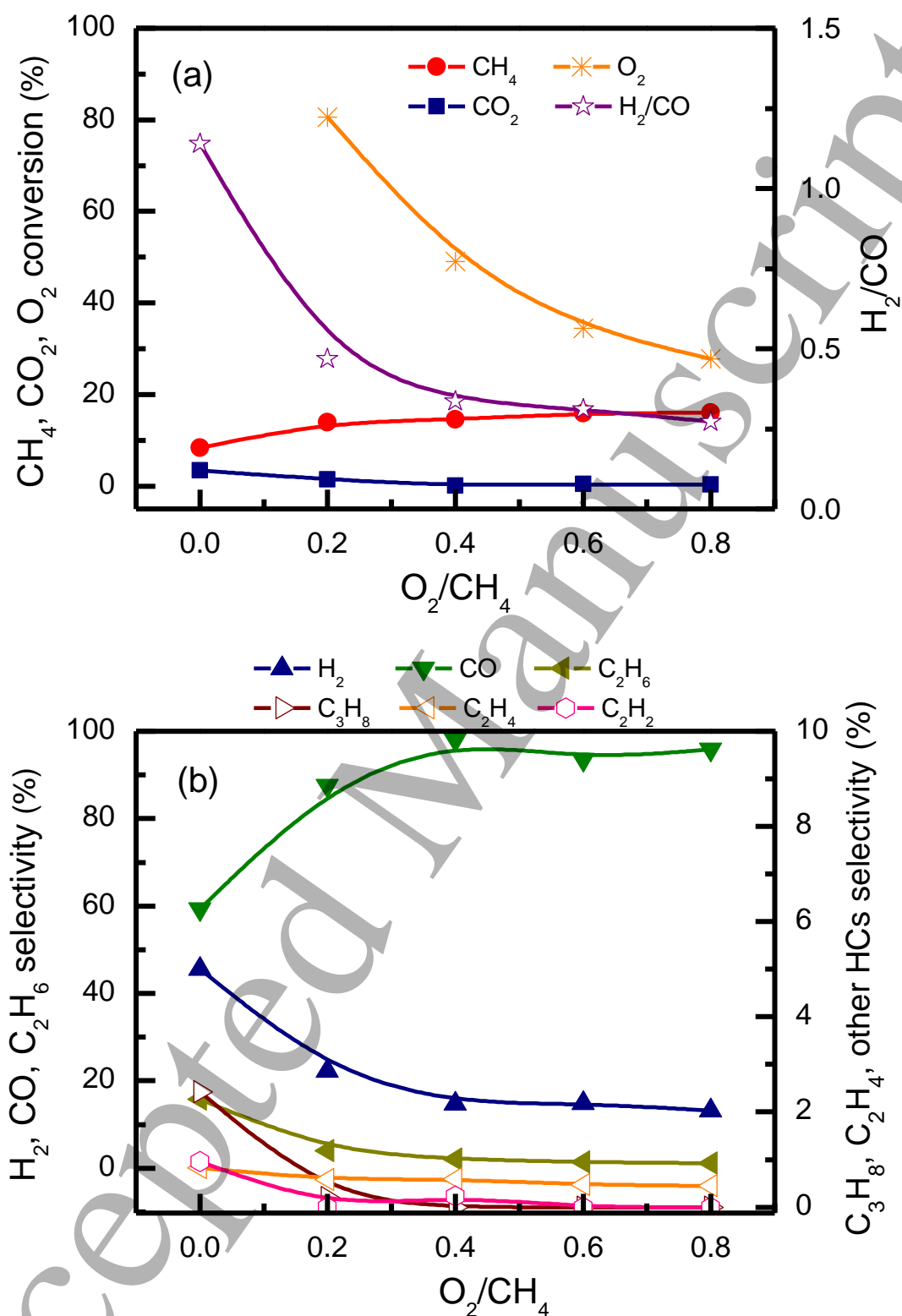


Figure 6. Effect of O_2/CH_4 value on the dry reforming of CH_4 (a) CH_4 , CO_2 , O_2 conversion and H_2/CO , and (b) H_2 , CO , C_2H_4 , C_2H_6 , C_3H_8 , and other HCs selectivity at

$P_{dis} = 10 \text{ W}$, $T=473 \text{ K}$.

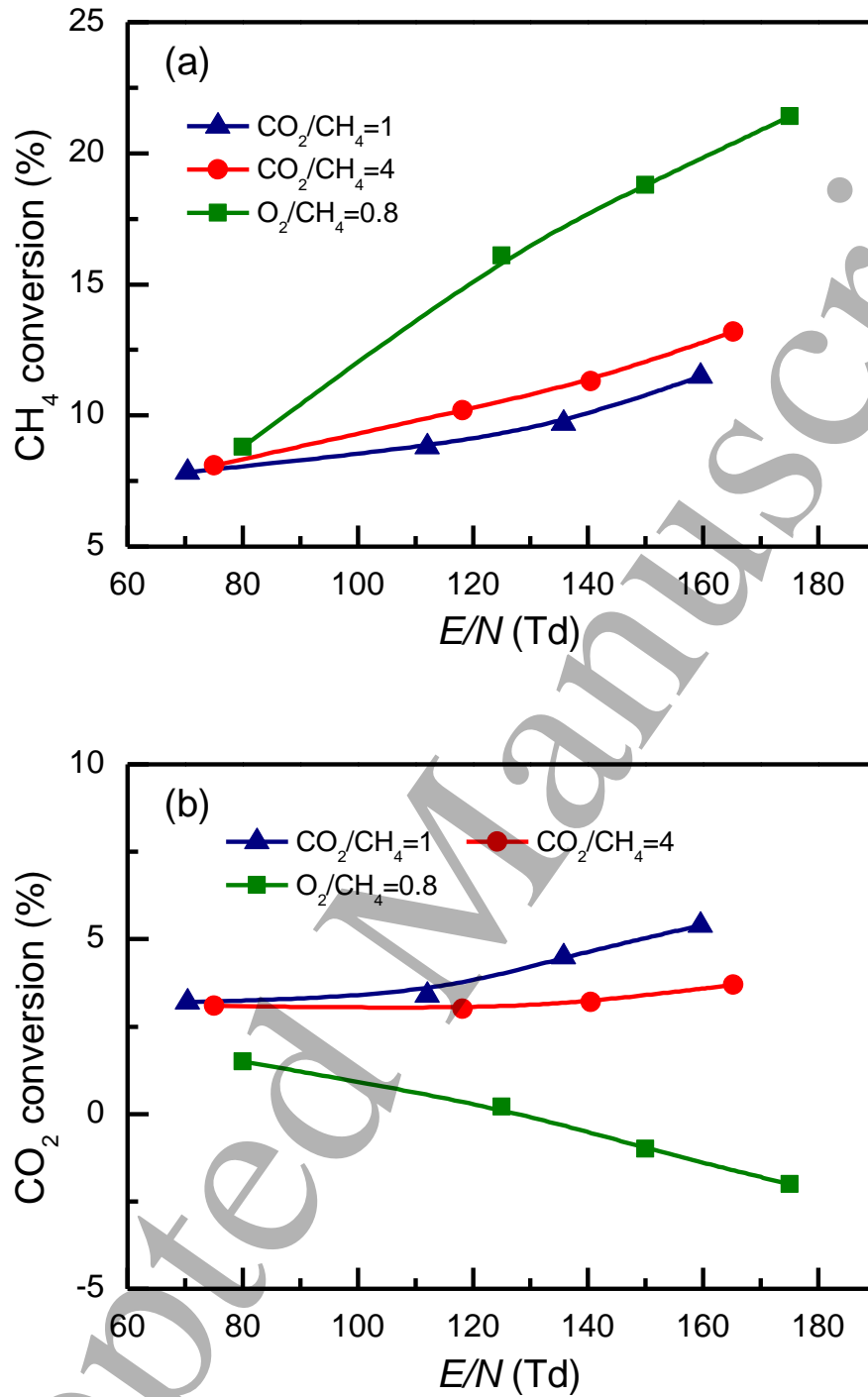
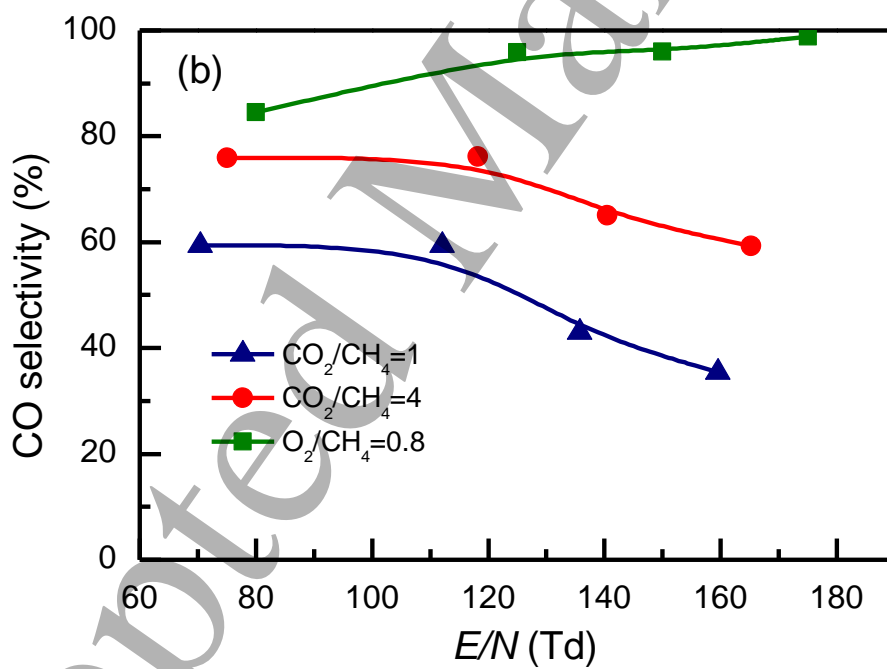
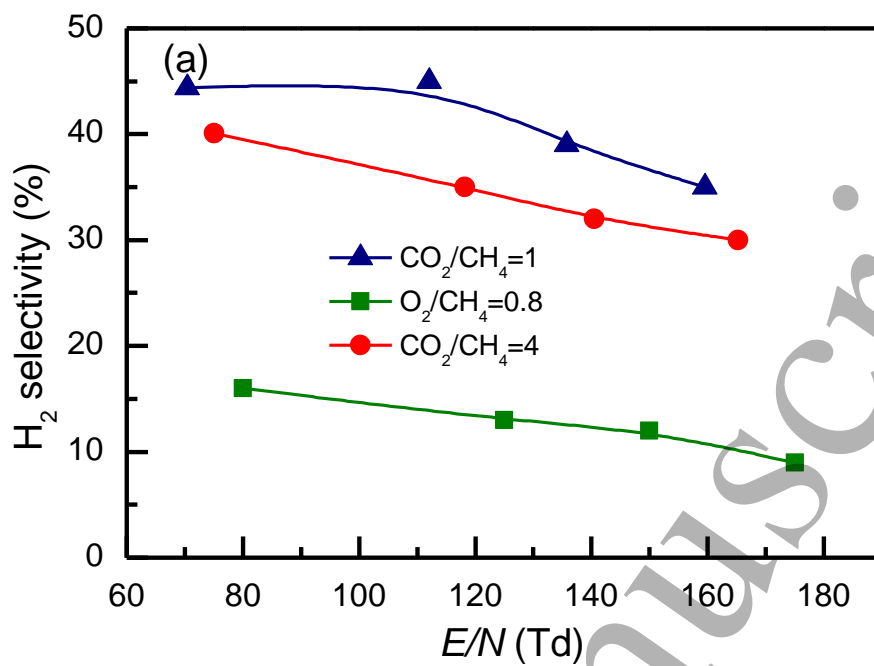


Figure 7. Effect of E/N value on the dry reforming of CH_4 (a) CH_4 conversion and (b) CO_2 conversion at $P_{dis} = 10 \text{ W}$.



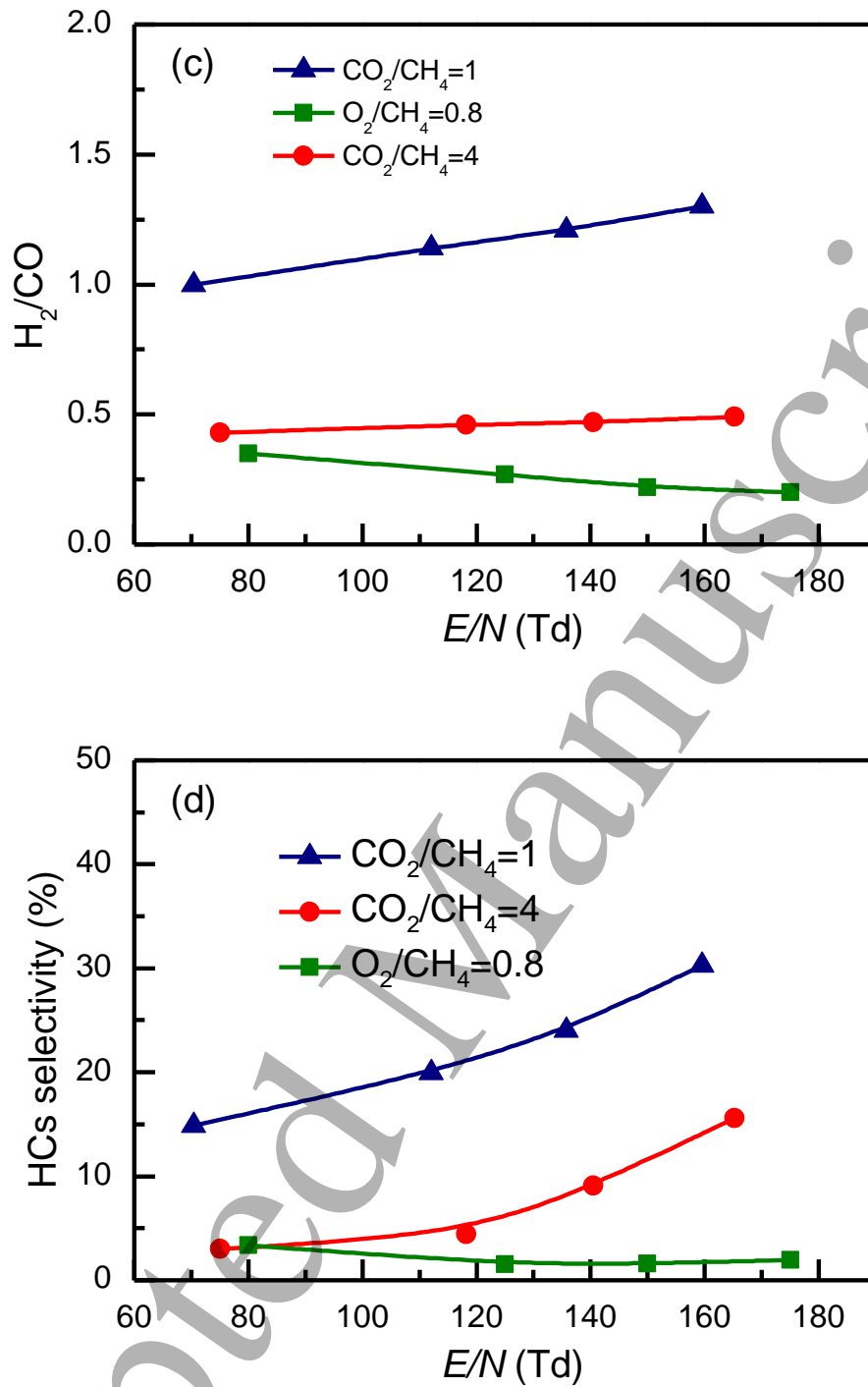
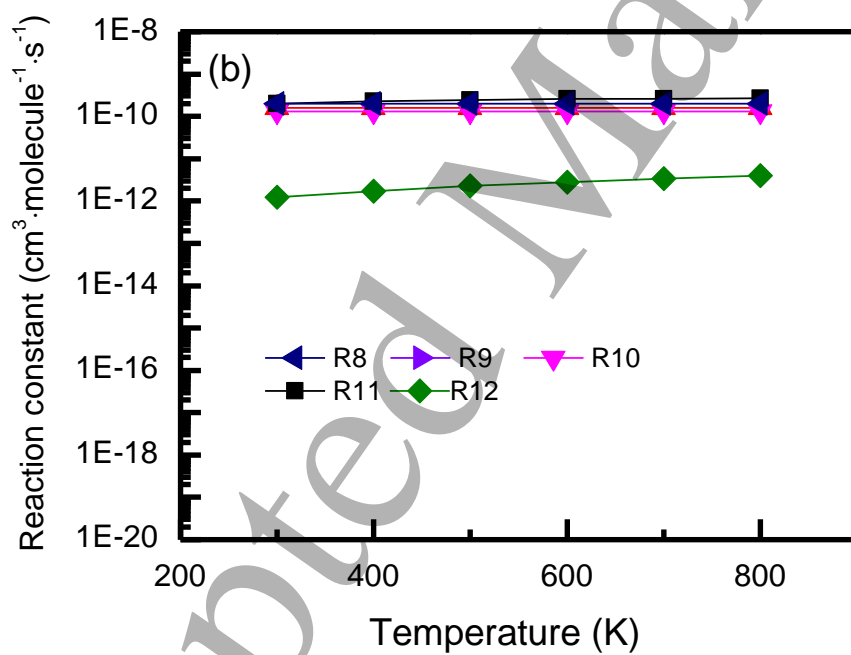
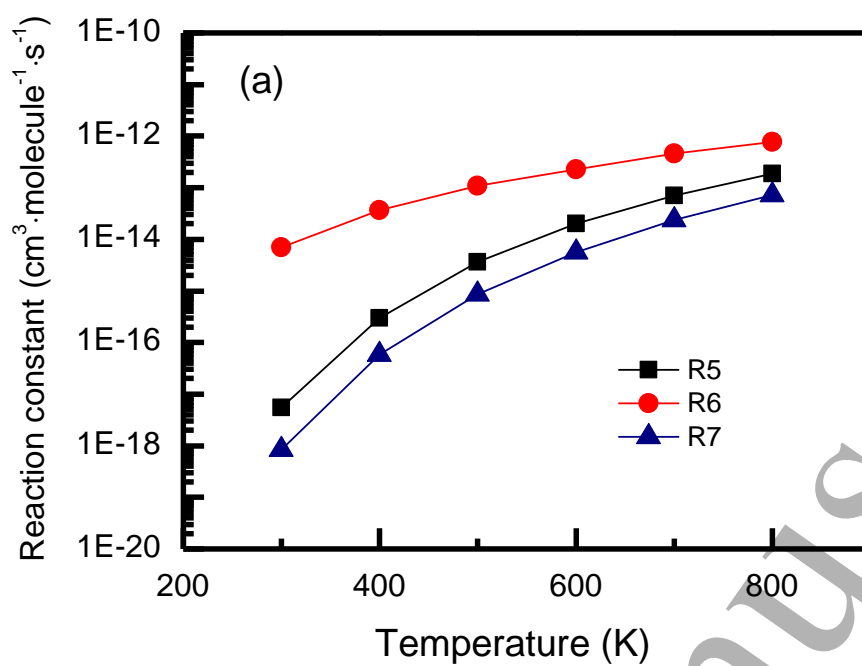
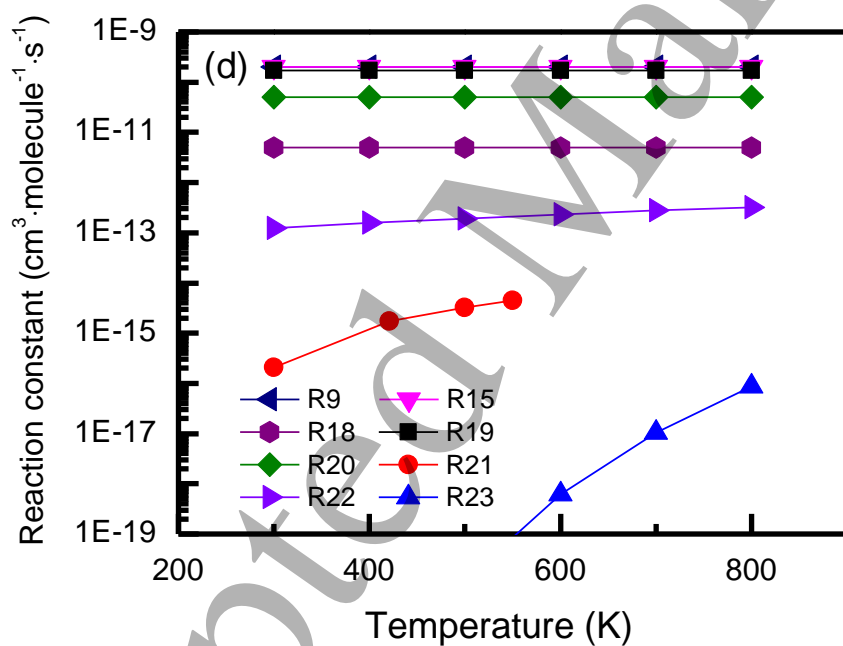
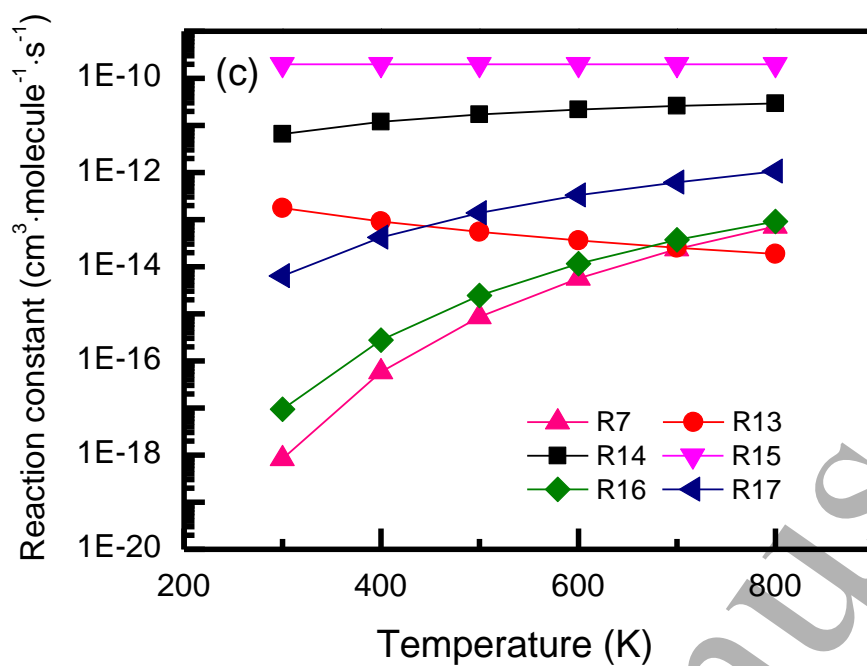


Figure 8. Effect of E/N value on the dry reforming of CH_4 (a) H_2 selectivity, (b) CO selectivity, (c) H_2/CO , and (d) HCs selectivity at $P_{dis} = 10$ W.





51 **Figure 9.** Reaction constants under different reaction temperatures: (a) CH_4 conversion;
52 (b) Competing reaction and CH_4 backward reaction; (c) H_2 production and consumption;
53 (d) CO production and consumption.